

EAST Search History

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|---|---|------------------|---------|---------------------|
| L1 | 439 | (substrate or wafer or semiconductor) with ((separat\$4 or independent\$5) with (inspect\$4)) with process\$5 | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 20:34 |
| L2 | 23 | 1 and "700"/\$.ccls. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 20:34 |
| L3 | 9 | independent\$5 with (develop\$4) with inspect\$4 with (wafer or substrate or semiconductor) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 20:41 |
| L4 | 198 | (independent\$4 with (wafer or substrate) with apparatus with inspect\$4).ab. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 20:43 |
| L5 | 1 | 4 and ("700"/\$.ccls. or "438"/\$.ccls.) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 20:44 |
| L6 | 5 | 4 and tokyo.as. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 20:49 |
| L7 | 8263 | substrate adj processing adj apparatus | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 20:50 |

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|-----|-----|--|---|----|----|---------------------|
| L8 | 24 | 7 and (independent\$4 near5 inspect\$5) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 20:50 |
| L9 | 429 | (coating with developing with apparatus).ab. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 21:06 |
| L10 | 19 | 9 and inspect\$4.ab. | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 21:06 |
| L11 | 14 | 10 and independent\$5 | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 21:12 |
| L12 | 7 | 10 and (flow near5 wafer) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 21:18 |
| L13 | 29 | 9 and (flow near5 wafer) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 21:18 |
| L14 | 3 | 13 and (reverse with route) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2008/05/19 21:25 |

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